

Substitute form 1449A/PTO		Complete if Known	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (use as many sheets as necessary)		Application Number	not yet assigned 10/796146
		Filing Date	concurrently herewith
		First Named Inventor	Daniel J.C. Herr
		Group Art Unit	
		Examiner Name	
Sheet 1 of 2	Attorney Docket Number	5347-204CT	

U.S. PATENTS AND PATENT PUBLICATIONS					
Examiner Initials*	Cite No.	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY
		Number	Kind Code (if known)		
<i>lu</i>	1.	US-3,582,176		Mathisen	06/1971
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<i>lu</i>	3.	US-4,498,771		Makosch et al;	02/1985
<i>lu</i>	4.	US-4,614,427		Koizumi et al;	09/1986
<i>lu</i>	5.	US-5,568,256		Koener et al; (Köner)	10/1996
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<i>lu</i>	8.	US-5,973,807		Buchkremer et al;	10/1999
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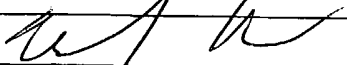
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Examiner Initials*	Cite No.	Foreign Patent Document			Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	T
		Office	Number	Kind Code (if known)			
<i>lu</i>	9.		11-329944		JPO (Abstract in English)	11/1999	
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<i>lu</i>	12.		03-295408		Japan	12/1991	
<i>lu</i>	13.		09-016062		Japan (Abstracts)	01/1997	

Examiner Signature	<i>[Signature]</i>	Date Considered	11/29/01
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Substitute form 1449A/PTO		Complete if Known	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (use as many sheets as necessary)		Application Number	10/7966110
		Filing Date	
		First Named Inventor	
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		Examiner Name	
Sheet 2 of 2	Attorney Docket Number		

OTHER NON PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published	T
u	14.	V. Georges et al; <i>Images charged objects using low-energy-electron coherent beams</i> , Ultramicroscopy 90 (2001) pp 32-38.	
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u	25.	Elliott, "Integrated Circuit Manufacturing Technology", pp 76-81 (1982)	
u	26.	Machine translation of Tetsuo et al., JP 11-329944	
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u	29.	J.C.H. Spence et al; <i>On the reconstruction of low voltage point projection holograms</i> ; Electron Holography, (1995) pp 267-276	
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u	34.	G. Morton et al; <i>Point Projector Electron Microscope</i> , Phy. Rev. Vol. 56, 705 (1939)	

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